

7. (Amended) Apparatus as claimed in claim 4, wherein said linear scanning device is a piezo-electric device.

8. (Amended) Apparatus as claimed in claim 2, wherein said apparatus further comprises an optical element upon which said sample beam is incident and said scanning device is an angular scanning device arranged to move said optical element.

10. (Amended) Apparatus as claimed in claim 1, wherein said apparatus includes a dual beam configuration.

11. (Amended) Apparatus as claimed in claim 1, wherein said cell comprises a first glass plate bonded to a second glass plate, said first plate having a flow channel formed therein and said second plate having reflection means deposited thereon.

12. (Amended) Method for measuring absorbance comprising:

transmitting a light beam through a cell having a sample area;

reflecting said light beam to a detector; and

modulating said sample beam such that said sample beam is moved from a first position in which said sample beam is incident upon said sample area to a second position in which said sample beam is incident upon said cell, thereby improving the sensitivity of an absorbance measurement.